

UNIVERSITI TEKNOLOGI MARA

**DEVELOPMENT AND FABRICATION OF
PIEZORESISTIVE MICROCANTILEVER-BASED
GLUCOSE BIOSENSOR**

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ABSTRACT

This thesis is focused on the *Development and Fabrication of the Piezoresistive Microcantilever-based Glucose Biosensor*. The objective of this work is to design via simulation a piezoresistive microcantilever sensor suitable for glucose sensing. Then, the piezoresistive microcantilever is fabricated with CMOS micromachining technique. The fabricated piezoresistive microcantilever performed the fabrication process characterization to prove the viability of the design. Finally, the objective in this work is to identify suitable Glucose immobilization technique onto microcantilever surface. The methodology of this work starts with the designing of piezoresistive microcantilever. The microcantilever beam length is selected at 195 μm and width, 70 μm . On this microcantilever beam there are four different piezoresistor with the length of 80 μm , 110 μm , 140 μm and 170 μm . The sacrificial layer of BPSG material in the piezoresistive microcantilever have two different thickness of 0.9 μm and 1.8 μm . The proposed biosensor also includes the fabrication process design and the process characteristic study such as the resistivity testing and wet etching characteristic study with wet etchant of Hydrofluoric (HF) acid, Pad Etchant and Buffered Oxide Etch (BOE) to observe the etching rate of the BPSG sacrificial layer. This investigation is important to observe the performance of the MEMS biosensor. Then, the signal conditioning circuit is developed to convert the physical behavior of the piezoresistive microcantilever to electrical signal. The signal conditioning circuit includes the wheatstone bridge, amplification, filtering and linearization circuitry. The next step is the investigation of several Glucose Oxidase (GOx) immobilization techniques on the fabricated microcantilever biosensor surface to find out the optimal enzyme immobilization. In this work there are two controlled conditions which is the glucose testing on the blank piezoresistive microcantilever and other is glucose testing on piezoresistive microcantilever immobilized without Glucose Oxidase (GOx). The proposed glucose-based MEMS biosensor has been developed and tested. The measurement obtained shows that at the testing of the glucose with blank microcantilever no resistance changes are observed indicates that no immobilization of receptor occurs with this technique. In the second method, the immobilization technique used normally is for the Au coated silicon microcantilever investigated previously by Jianhong et al. With this technique, GOx immobilized PZR microcantilever sensor found there is a resistance change caused by a change in surface stress in response to the microcantilever deflection. The measurement obtained shows the possibility use of piezoresistive microcantilever for glucose testing.

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TABLE OF CONTENTS

TITLE PAGE	
CANDIDATE’S DECLARATION	ii
ABSTRACT	iii
ACKNOWLEDGEMENT	iv
DEDICATION	v
TABLE OF CONTENTS	vi
LIST OF TABLES	xi
LIST OF FIGURES	xiii
LIST OF PLATES	xviii
LIST OF ABBREVIATIONS	xix
LIST OF SYMBOLS	xx
CHAPTER 1: INTRODUCTION	
1.1 Background	1
1.2 Problem Statement	2
1.3 Statement of Purpose and Objectives	3
1.4 Scope of Work	4
1.5 Thesis Outline	5
CHAPTER 2: LITERATURE REVIEW OF MICROCANTILEVER- BASED GLUCOSE BIOSENSORS	
2.1 Introduction	7
2.2 Biosensor Technology	7
2.3 Enzyme-based Biosensor	8
2.4 Glucose Sensing	8
2.5 MEMS Device	9
2.5.1 MEMS Devices Market Survey	10
2.6 Microcantilever Device in MEMS	12
2.6.1 Microcantilever Deflection Detection schemes	13

2.6.1.1	Static sensing method	14
2.6.2	Review of Microcantilever sensor type	15
2.6.2.1	Capacitive Microcantilever sensor	15
2.6.2.2	Piezoelectric Microcantilever sensor	16
2.6.2.3	Piezoresistive (PZR) Microcantilever sensor	17
2.6.3	Microcantilever sensor in glucose sensing	18
2.7	PZR Microcantilever Design	20
2.7.1	Materials selection	21
2.7.2	Selection of microfabrication process	23
2.8	Operational Principle of the PZR Microcantilever	
	Structure Design	24
2.8.1	Stress measurement in microcantilever deposited layers	26
2.9	Mathematical Analysis of PZR Microcantilever Beam Deflections	
2.9.1	Introduction	28
2.9.2	Stress and equilibrium concept in FEA	29
2.9.3	Relationship between microcantilever beam deflection and stress	30
2.9.4	Deflection of fixed-free end microcantilever beam analysis	33
2.9.5	Stress field effect on resistance change in piezoresistor	34

CHAPTER 3: DESIGN SIMULATION AND ANALYSIS OF PIEZORESISTIVE (PZR) MICROCANTILEVER

3.1	Introduction	39
3.2	Methodology	40
3.3	Results and Discussion	
3.3.1	Effects of Microcantilever Beam Thickness on PZR Microcantilever Deflection	47
3.4	Analysis on the Effects of Force Variation Applied with Different PZR Microcantilever length	52
3.4.1	Piezoresistor length of 80 μ m	52
3.4.2	Piezoresistor length of 110 μ m	53